

The documentation and process conversion measures necessary to comply with this revision shall be completed by 1 November 2014

INCH-POUND

MIL-PRF-19500/703D
 1 September 2014
 SUPERSEDING
 MIL-PRF-19500/703C
 26 February 2014

PERFORMANCE SPECIFICATION SHEET

SEMICONDUCTOR DEVICE, FIELD EFFECT RADIATION HARDENED
 TRANSISTOR, N-CHANNEL, SILICON, TYPES 2N7479U3, 2N7480U3, AND 2N7481U3,
 JANTXVR, F, G, AND H AND JANSR, F, G, AND H

This specification is approved for use by all Departments and Agencies of the Department of Defense.

The requirements for acquiring the product described herein shall consist of this specification sheet and [MIL-PRF-19500](#).

1. SCOPE

1.1 Scope. This specification covers the performance requirements for a N-Channel, enhancement-mode, MOSFET, radiation hardened, power transistor. Two levels of product assurance are provided for each device type as specified in [MIL-PRF-19500](#), with avalanche energy maximum rating (E_{AS}) and maximum avalanche current (I_{AS}).

1.2 Physical dimensions. See [figure 1](#), surface mount, TO-276AA (SMD-0.5) for U3.

1.3 Maximum ratings. $T_A = +25^\circ\text{C}$, unless otherwise specified.

Type	P_T (1) $T_C = +25^\circ\text{C}$	P_T $T_A = +25^\circ\text{C}$	$R_{\theta JC}$ (2)	V_{DS}	V_{DG}	V_{GS}	I_{D1} (3) (4) $T_C = +25^\circ\text{C}$	I_{D2} (3) (4) $T_C = +100^\circ\text{C}$	I_S	I_{DM} (5)	T_J and T_{STG}
	<u>W</u>	<u>W</u>	<u>$^\circ\text{C/W}$</u>	<u>V dc</u>	<u>V dc</u>	<u>V dc</u>	<u>A dc</u>	<u>A dc</u>	<u>A dc</u>	<u>A (pk)</u>	<u>$^\circ\text{C}$</u>
2N7479U3	75	1.0	1.67	30	30	± 20	22	22	22	88	-55
2N7480U3	75	1.0	1.67	60	60	± 20	22	21	22	88	to
2N7481U3	75	1.0	1.67	100	100	± 20	22	16	22	88	+150

- (1) Derate linearly by 0.6 W/ $^\circ\text{C}$ for $T_C > +25^\circ\text{C}$.
- (2) See [figure 2](#), thermal impedance curves.
- (3) The following formula derives the maximum theoretical I_D limit. I_D is limited by package and internal construction.

$$I_D = \sqrt{\frac{T_{JM} - T_C}{(R_{\theta JC}) \times (R_{DS(on)} \text{ at } T_{JM})}}$$

- (4) See [figure 3](#), maximum drain current graph.
- (5) $I_{DM} = 4 \times I_{D1}$ as calculated in note (3).

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1.4 Primary electrical characteristics at $T_C = +25^\circ\text{C}$.

Type	Min $V_{(BR)DSS}$ $V_{GS} = 0$ $I_D = 1.0\text{mA dc}$	$V_{GS(TH)1}$ $V_{DS} \geq V_{GS}$ $I_D = 1.0\text{ mA dc}$	Max I_{DSS1} $V_{GS} = 0$ $V_{DS} = 80\%$ of rated V_{DS}	Max $r_{DS(on)}$ (1) $V_{GS} = 12\text{V}, I_D = I_{D2}$		E_{AS}
				$T_J = +25^\circ\text{C}$	$T_J = +150^\circ\text{C}$	
	<u>V dc</u>	<u>V dc</u> Min Max	<u>$\mu\text{A dc}$</u>	<u>Ω</u>	<u>Ω</u>	<u>mJ</u>
2N7479U3	30			0.020	0.040	155
2N7480U3	60	2.0 4.0	10	0.030	0.068	100
2N7481U3	100			0.060	0.115	70

(1) Pulsed (see 4.5.1).

2. APPLICABLE DOCUMENTS

2.1 General. The documents listed in this section are specified in sections 3 and 4 of this specification. This section does not include documents cited in other sections of this specification or recommended for additional information or as examples. While every effort has been made to ensure the completeness of this list, document users are cautioned that they must meet all specified requirements of documents cited in sections 3 and 4 of this specification, whether or not they are listed.

2.2 Government documents.

2.2.1 Specifications, standards, and handbooks. The following specifications, standards, and handbooks form a part of this document to the extent specified herein. Unless otherwise specified, the issues of these documents are those cited in the solicitation or contract.

DEPARTMENT OF DEFENSE SPECIFICATIONS

[MIL-PRF-19500](#) - Semiconductor Devices, General Specification for.

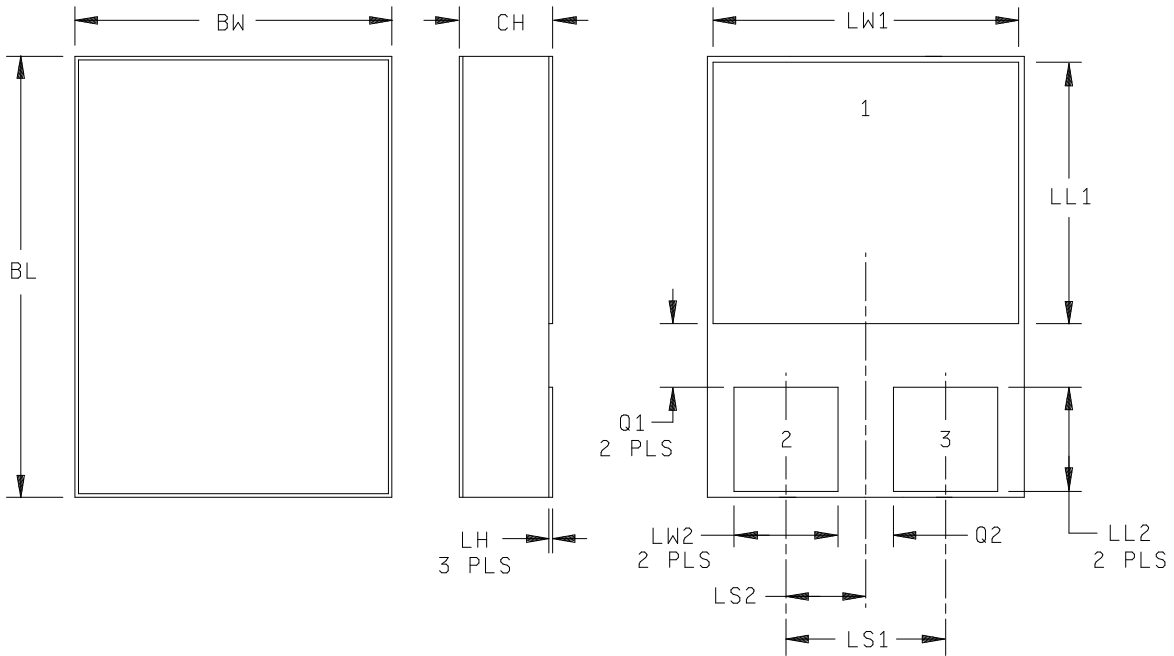
DEPARTMENT OF DEFENSE STANDARDS

[MIL-STD-750](#) - Test Methods for Semiconductor Devices.

(Copies of these documents are available online at <http://quicksearch.dla.mil/>).

2.3 Order of precedence. Unless otherwise noted herein or in the contract, in the event of a conflict between the text of this document and the references cited herein, the text of this document takes precedence. Nothing in this document, however, supersedes applicable laws and regulations unless a specific exemption has been obtained.

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Symbol	Dimensions			
	Inches		Millimeters	
	Min	Min	Min	Max
BL	.395	.405	10.03	10.29
BW	.291	.301	7.39	7.65
CH	.1085	.1205	2.76	3.06
LH	.010	.020	0.25	0.51
LW1	.281	.291	7.14	7.39
LW2	.090	.100	2.29	2.54
LL1	.220	.230	5.59	5.84
LL2	.115	.125	2.92	3.18
LS1	0.150 BSC		3.81 BSC	
LS2	0.075 BSC		1.91 BSC	
Q1	.030		0.762	
Q2	.030		0.762	
TERM 1	Drain			
TERM 2	Gate			
TERM 3	Source			

NOTES:

1. Dimensions are in inches.
2. Millimeters are given for general information only.
3. The lid shall be electrically isolated from the drain, gate and source.

FIGURE 1. Physical dimensions for TO-276AA (SMD-0.5), U3.

3. REQUIREMENTS

3.1 General. The individual item requirements shall be as specified in [MIL-PRF-19500](#) and as modified herein.

3.2 Qualification. Devices furnished under this specification shall be products that are manufactured by a manufacturer authorized by the qualifying activity for listing on the applicable qualified manufacturer's list (QML) before contract award (see [4.2](#) and [6.3](#)).

3.3 Abbreviations, symbols, and definitions. Abbreviations, symbols, and definitions used herein shall be as specified in [MIL-PRF-19500](#) and as follows.

I_{AS} Rated avalanche current, nonrepetitive
nC nano Coulomb.

3.4 Interface and physical dimensions. Interface and physical dimensions shall be as specified in [MIL-PRF-19500](#), and on [figure 1](#) (TO-276AA, SMD-0.5, U3) herein.

3.4.1 Lead finish. Lead finish shall be solderable in accordance with [MIL-PRF-19500](#), [MIL-STD-750](#), and herein. Where a choice of lead finish is desired, it shall be specified in the acquisition document (see [6.2](#)).

* 3.4.2 Multiple chip construction. Multiple chip construction is not permitted to meet the requirements of this specification.

3.5 Electrostatic discharge protection. The devices covered by this specification require electrostatic discharge protection.

3.5.1 Handling. Metal oxide semiconductor (MOS) devices must be handled with certain precautions to avoid damage due to the accumulation of static charge. However, the following handling practices are recommended (see [3.5](#)).

- a. Devices should be handled on benches with conductive handling devices.
- b. Ground test equipment, tools, and personnel handling devices.
- c. Do not handle devices by the leads.
- d. Store devices in conductive foam or carriers.
- e. Avoid use of plastic, rubber, or silk in MOS areas.
- f. Maintain relative humidity above 50 percent if practical.
- g. Care should be exercised during test and troubleshooting to apply not more than maximum rated voltage to any lead.
- h. Gate must be terminated to source, $R \leq$ or 100 k Ω , whenever bias voltage is applied drain to source.

3.6 Electrical performance characteristics. Unless otherwise specified herein, the electrical performance characteristics are as specified in [1.3](#), [1.4](#), and [table I](#).

3.7 Electrical test requirements. The electrical test requirements shall be as specified in [table I](#).

* 3.8 Marking. Marking shall be in accordance with [MIL-PRF-19500](#).

3.9 Workmanship. Semiconductor devices shall be processed in such a manner as to be uniform in quality and shall be free from other defects that will affect life, serviceability, or appearance.

4. VERIFICATION

4.1 Classification of inspections. The inspection requirements specified herein are classified as follows:

- a. Qualification inspection (see 4.2).
- b. Screening (see 4.3).
- c. Conformance inspection (see 4.4 and tables I and II).

4.2 Qualification inspection. Qualification inspection shall be in accordance with MIL-PRF-19500 and as specified herein.

4.2.1 Group E qualification. Group E inspection shall be performed for qualification or re-qualification only. In case qualification was awarded to a prior revision of the specification sheet that did not request the performance of table III tests, the tests specified in table III herein that were not performed in the prior revision shall be performed on the first inspection lot of this revision to maintain qualification.

4.2.1.1 Single Event Effects (SEE). SEE shall be performed at initial qualification and after process or design changes which may affect radiation hardness (see table III and table IV). Upon qualification, manufacturers shall provide the verification test conditions from section 5 of method 1080 of MIL-STD-750 that were used to qualify the device for inclusion into section 6 of the slash sheet. End-point measurements shall be in accordance with table II. SEE characterization data shall be made available upon request of the qualifying or acquiring activity.

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* 4.3 Screening (JANS and JANTXV). Screening shall be in accordance with table E-IV of MIL-PRF-19500, and as specified herein. The following measurements shall be made in accordance with table I herein. Devices that exceed the limits of table I herein shall not be acceptable.

Screen (see table E-IV of MIL-PRF-19500) (1) (2)	Measurement	
	JANS level	JANTXV levels
(3)	Gate stress test (see 4.3.1)	Gate stress test (see 4.3.1)
(3)	Method 3470 of MIL-STD-750, E _{AS} (see 4.3.2)	Method 3470 of MIL-STD-750, E _{AS} (see 4.3.2)
(3) 3c	Method 3161 of MIL-STD-750, thermal impedance, (see 4.3.3)	Method 3161 of MIL-STD-750, thermal impedance, (see 4.3.3)
9	Subgroup 2 of table I herein, I _{GSSF1} , I _{GSSR1} , I _{DSS1} as a minimum	Not applicable
10	Method 1042 of MIL-STD-750, test condition B	Method 1042 of MIL-STD-750, test condition B
11	I _{GSSF1} , I _{GSSR1} , I _{DSS1} , r _{DS(on)1} , V _{GS(TH)1} Subgroup 2 of table I herein ΔI _{GSSF1} = ±20 nA dc or ±100 percent of initial value, whichever is greater. ΔI _{GSSR1} = ±20 nA dc or ±100 percent of initial value, whichever is greater. ΔI _{DSS1} = ±10 μA dc or ±100 percent of initial value, whichever is greater.	I _{GSSF1} , I _{GSSR1} , I _{DSS1} , r _{DS(on)1} , V _{GS(TH)1} Subgroup 2 of table I herein
12	Method 1042 of MIL-STD-750, test condition A	Method 1042 of MIL-STD-750, test condition A
13	Subgroups 2 and 3 of table I herein ΔI _{GSSF1} = ±20 nA dc or ±100 percent of initial value, whichever is greater. ΔI _{GSSR1} = ±20 nA dc or ±100 percent of initial value, whichever is greater. ΔI _{DSS1} = ±10 μA dc or ±100 percent of initial value, whichever is greater. Δr _{DS(on)1} = ±20 percent of initial value ΔV _{GS(th)1} = ±20 percent of initial value	Subgroups 2 and 3 of table I herein ΔI _{GSSF1} = ±20 nA dc or ±100 percent of initial value, whichever is greater. ΔI _{GSSR1} = ±20 nA dc or ±100 percent of initial value, whichever is greater. ΔI _{DSS1} = ±10 μA dc or ±100 percent of initial value, whichever is greater. Δr _{DS(on)1} = ±20 percent of initial value ΔV _{GS(th)1} = ±20 percent of initial value
17	For U3 packages: Method 1081 of MIL-STD-750 (see 4.3.4), Endpoints: Subgroup 2 of table I herein.	For U3 packages: Method 1081 of MIL-STD-750 (see 4.3.4), Endpoints: Subgroup 2 of table I herein.

- (1) At the end of the test program, I_{GSSF1}, I_{GSSR1}, and I_{DSS1} are measured.
- (2) An out-of-family program to characterize I_{GSSF1}, I_{GSSR1}, I_{DSS1}, V_{GS(th)1} and r_{DS(ON)1} shall be invoked.
- (3) Shall be performed anytime before screen 9.

4.3.1 Gate stress test. Apply $V_{GS} = 24$ V, minimum for $t = 250$ μ S, minimum.

4.3.2 Single pulse avalanche energy (E_{AS}).

a. Peak current $I_{AS} = I_{D1}$.

b. Inductance $L = \left[\frac{2E_{AS}}{(I_{D1})^2} \right] \left[\frac{V_{BR} - V_{DD}}{V_{BR}} \right]$ mH minimum.

c. Gate to source resistor R_{GS} $25 \Omega \leq R_{GS} \leq 200 \Omega$.

d. Supply voltage $V_{DD} = 25$ V dc, except $V_{DD} = 50$ V dc for 2N7481U3.

e. Initial case temperature..... $T_C = +25^\circ$ C, -5° C, $+10^\circ$ C.

f. Gate voltage $V_{GS} = 12$ V dc.

g. Number of pulses to be applied 1 pulse minimum.

4.3.3 Thermal impedance. The thermal impedance measurements shall be performed in accordance with method 3161 of [MIL-STD-750](#) using the guidelines in that method for determining I_M , I_H , t_H , t_{SW} , (and V_H where appropriate). Measurement delay time (t_{MD}) = 70 μ s max. See [table III](#), group E, subgroup 4 herein.

* 4.3.4 Dielectric withstanding voltage.

a. Magnitude of test voltage.....600 V dc.

b. Duration of application of test voltage.....15 seconds (min).

c. Points of application of test voltage.....All pads to case.

d. Method of connection.....Mechanical.

e. Kilovolt-ampere rating of high voltage source.....1,200 V/1.0 mA (min).

f. Maximum leakage current.....1.0 mA.

g. Voltage ramp up time.....500 V/second

4.4 Conformance inspection. Conformance inspection shall be in accordance with [MIL-PRF-19500](#).

4.4.1 Group A inspection. Group A inspection shall be conducted in accordance with table E-V of [MIL-PRF-19500](#) and [table I](#) herein.

4.4.2 Group B inspection. Group B inspection shall be conducted in accordance with the conditions specified for subgroup testing in table E-VIA (JANS) and table E-VIB (JANTXV) of [MIL-PRF-19500](#), and as follows. Electrical measurements (end-points) shall be in accordance with [table I](#), subgroup 2 herein.

4.4.2.1 Group B inspection, table E-VIA (JANS) of MIL-PRF-19500.

<u>Subgroup</u>	<u>Method</u>	<u>Condition</u>
B3	1051	Test condition G, 100 cycles.
B3	2077	Scanning electron microscope (SEM).
B4	1042	Intermittent operation life, condition D. No heat sink or forced-air cooling on the device shall be permitted during the on cycle. $t_{on} = 30$ seconds minimum.
B5	1042	Accelerated steady-state gate bias, condition B, $V_{GS} = \text{rated}$; $T_A = +175^\circ\text{C}$, $t = 24$ hours minimum; or $T_A = +150^\circ\text{C}$, $t = 48$ hours minimum.
B5	1042	Accelerated steady-state reverse bias, condition A, $V_{DS} = \text{rated}$; $T_A = +175^\circ\text{C}$, $t = 120$ hours minimum; or $T_A = +150^\circ\text{C}$, $t = 240$ hours minimum.
B5	2037	Bond strength, test condition D.

4.4.2.2 Group B inspection, table E-VIB (JANTXV) of MIL-PRF-19500.

<u>Subgroup</u>	<u>Method</u>	<u>Condition</u>
B2	1051	Test condition G, 25 cycles.
B3	1042	Intermittent operation life, condition D. No heat sink or forced-air cooling on the device shall be permitted during the on cycle. $t_{on} = 30$ seconds minimum.
B5 and B6		Not applicable.

4.4.3 Group C inspection. Group C inspection shall be conducted in accordance with the conditions specified for subgroup testing in table E-VII of MIL-PRF-19500 and as follows. Electrical measurements (end-points) shall be in accordance with [table I](#), subgroup 2 herein.

<u>Subgroup</u>	<u>Method</u>	<u>Condition</u>
C2	2036	Terminal strength is not applicable.
C5	3161	Thermal resistance, see 4.3.3 , $R_{\theta JC(\text{max})} = 1.67^\circ\text{C/W}$.
C6	1042	Intermittent operation life, condition D. No heat sink or forced-air cooling on the device shall be permitted during the on cycle. $t_{on} = 30$ seconds minimum.

4.4.4 Group D inspection. Group D inspection shall be conducted in accordance with table E-VIII of MIL-PRF-19500 and [table II](#) herein.

4.4.5 Group E inspection. Group E inspection shall be conducted in accordance with the conditions specified for subgroup testing in table E-IX of MIL-PRF-19500 and as specified in [table III](#) herein. Electrical measurements (end-points) shall be in accordance with [table I](#), subgroup 2 herein.

4.4.5.1 SEE. Design capability shall be tested on the initial qualification and thereafter whenever a major die design or process change is introduced. See the design safe operation area figure. End-point measurements shall be in accordance with [table III](#).

4.5 Methods of inspection. Methods of inspection shall be as specified in the appropriate tables and as follows.

4.5.1 Pulse measurements. Conditions for pulse measurement shall be as specified in section 4 of MIL-STD-750.

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* TABLE I. Group A inspection.

Inspection <u>1</u> /	MIL-STD-750		Symbol	Limits		Unit
	Method	Condition		Min	Max	
<u>Subgroup 1</u>						
Visual and mechanical inspection	2071					
<u>Subgroup 2</u>						
Thermal impedance <u>2</u> /	3161	See 4.3.3	$Z_{\theta JC}$			°C/W
Breakdown voltage drain to source 2N7479U3 2N7480U3 2N7481U3	3407	Bias condition C, $V_{GS} = 0$, $I_D = 1$ mA dc	$V_{(BR)DSS}$	30 60 100		V dc V dc V dc
Gate to source voltage (threshold)	3403	$V_{DS} \geq V_{GS}$, $I_D = 1$ mA dc	$V_{GS(TH)1}$	2.0	4.0	V dc
Gate current	3411	$V_{GS} = +20$ V dc, bias condition C, $V_{DS} = 0$	I_{GSSF1}		+100	nA dc
Gate current	3411	$V_{GS} = -20$ V dc, bias condition C, $V_{DS} = 0$	I_{GSSR1}		-100	nA dc
Drain current	3413	$V_{GS} = 0$, bias condition C, $V_{DS} = 80$ percent of rated V_{DS} ,	I_{DSS1}		10	μA dc
Static drain to source on-state resistance 2N7479U3 2N7480U3 2N7481U3	3421	$V_{GS} = 12$ V dc, condition A, pulsed (see 4.5.1), $I_D = I_{D2}$	$r_{DS(ON)1}$		0.020 0.030 0.060	Ω Ω Ω
* Forward voltage 2N7479U3 2N7480U3 2N7481U3	4011	$V_{GS} = 0$, condition B, pulsed (see 4.5.1), $I_D = I_{D1}$	V_{SD}		1.2 1.2 1.2	V dc V dc V dc

See footnotes at end of table.

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* TABLE I. Group A inspection - Continued.

Inspection <u>1/</u>	MIL-STD-750		Symbol	Limits		Unit
	Method	Condition		Min	Max	
<u>Subgroup 3</u>						
High temperature operation		$T_C = T_J = +125^\circ\text{C}$				
Gate current	3411	$V_{GS} = \pm 20\text{ V dc}$, bias condition C, $V_{DS} = 0$	I_{GSS2}		± 200	nA dc
Drain current	3413	$V_{GS} = 0$, bias condition C, $V_{DS} = 80$ percent of rated V_{DS}	I_{DSS2}		25	$\mu\text{A dc}$
Static drain to source on-state resistance	3421	$V_{GS} = 12\text{ V dc}$, condition A, pulsed (see 4.5.1), $I_D = I_{D2}$	$r_{DS(ON)3}$			
2N7479U3					0.035	Ω
2N7480U3					0.060	Ω
2N7481U3					0.110	Ω
Gate to source voltage (threshold)	3403	$V_{DS} \geq V_{GS}$, $I_D = 1\text{ mA dc}$	$V_{GS(TH)2}$	1.0		V dc
Low temperature operation		$T_C = T_J = -55^\circ\text{C}$				
Gate to source voltage (threshold)	3403	$V_{DS} \geq V_{GS(TH)3}$, $I_D = 1\text{ mA dc}$	$V_{GS(TH)3}$		5.0	V dc
<u>Subgroup 4</u>						
Forward transconductance	3475	$I_D = I_{D2}$, $V_{DD} = 15\text{ V dc}$ (see 4.5.1)	g_{FS}			
2N7479U3				16		S
2N7480U3				16		S
2N7481U3				13		S
Switching time test	3472	$I_D = I_{D1}$, $V_{GS} = 12\text{ V dc}$, $R_G = 2.35\ \Omega$, $V_{DD} = 50$ percent of rated V_{DS}				
Turn-on delay time			$t_{D(on)}$		25	ns
Rise time			t_r		100	ns
Turn-off delay time			$t_{D(off)}$		35	ns
Fall time			t_f		30	ns

See footnotes at end of table.

* TABLE I. Group A inspection - Continued.

Inspection <u>1/</u>	MIL-STD-750		Symbol	Limits		Unit
	Method	Condition		Min	Max	
<u>Subgroup 5</u>						
Safe operating area test (high voltage)	3474	See figures 4, 5, and 6 $t_p = 10$ ms min. $V_{DS} = 80$ percent of max. rated V_{DS}				
Electrical measurements		See table I , subgroup 2				
<u>Subgroup 6</u>						
Not applicable						
<u>Subgroup 7</u>						
Gate charge	3471	Condition B. $I_D = I_{D1}$, $V_{GS} = 12$ V dc $V_{DD} = 50$ percent of rated V_{DS}				
On-state gate charge			$Q_{G(ON)}$			
2N7479U3				65		nC
2N7480U3				45		nC
2N7481U3				50		nC
Gate to source charge			Q_{GS}			
2N7479U3				20		nC
2N7480U3				10		nC
2N7481U3				7.4		nC
Gate to drain charge			Q_{GD}			
2N7479U3				10		nC
2N7480U3				15		nC
2N7481U3				20		nC
* Reverse recovery time	3473	Condition A, $di/dt = -100$ A/ μ s, $V_{DD} \leq V_{(BR)DSS}$ $I_D = I_{D1}$	t_{rr}			
2N7479U3				102		ns
2N7480U3				125		ns
2N7481U3				250		ns

1/ For sampling plan, see [MIL-PRF-19500](#).

2/ This test required for the following end-point measurements only (not intended for [4.3](#), screen 9 or 11):
 Group B, subgroups 2 and 3 (JANTXV).
 Group B, subgroups 3 and 4 (JANS).
 Group C, subgroup 6.
 Group E, subgroup 1.

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* TABLE II. Group D inspection.

Inspection 1/ 2/ 3/	MIL-STD-750		Symbol	Pre-irradiation limits		Post-irradiation limits				Unit
	Method	Conditions		R, F, G and H		R, F and G		H 4/		
				Min	Max	Min	Max	Min	Max	
<u>Subgroup 1</u>										
Not applicable										
<u>Subgroup 2</u>										
T _C = + 25°C										
Steady-state total dose irradiation (V _{GS} bias) 5/	1019	V _{GS} = 12 V; V _{DS} = 0								
Steady-state total dose irradiation (V _{DS} bias) 5/	1019	V _{GS} = 0; V _{DS} = 80 percent of rated V _{DS} (preirradiation)								
End-point electricals:										
Breakdown voltage, drain to source 2N7479U3 2N7480U3 2N7481U3	3407	V _{GS} = 0 V; I _D = 1 mA; bias condition C	V _{(BR)DSS}	30 60 100		30 60 100		30 60 100		V dc V dc V dc
Gate to source voltage (threshold)	3403	V _{DS} ≥ V _{GS} I _D = 1 mA	V _{GS(th)1}	2.0	4.0	2.0	4.0	1.5	4.0	V dc
Gate current	3411	V _{GS} = +20 V; V _{DS} = 0 bias condition C	I _{GSSF1}		100		100		100	nA dc
Gate current	3411	V _{GS} = -20 V; V _{DS} = 0 bias condition C	I _{GSSR1}		-100		-100		-100	nA dc
Drain current	3413	V _{GS} = 0, V _{DS} = 80 percent of rated V _{DS} (preirradiation) bias condition C,	I _{DSS}		10		10		25	μA dc
Static drain to source on-state voltage 2N7479U3 2N7480U3 2N7481U3	3405	V _{GS} = 12 V; I _D = I _{D2} condition A pulsed (see 4.5.1)	V _{DS(on)}		0.528 0.714 1.024		0.528 0.714 1.024		0.660 0.903 1.280	V dc V dc V dc
Forward voltage source drain diode	4011	V _{GS} = 0; I _D = I _{D1} bias condition C	V _{SD}		1.2		1.2		1.2	V dc

1/ For sampling plan see MIL-PRF-19500.

2/ Group D qualification may be performed prior to lot formation. Wafers qualified to these group D QCI requirements may be used for any other specification sheet utilizing the same die design.

3/ At the manufacturer's option, group D samples need not be subjected to the screening tests, and may be assembled in it's qualified package or in any qualified package that the manufacturer has data to correlate the performance to the designated package.

* 4/ The H designation represents devices which pass end-points at all 100K, 300K, 500K and 1000K rads (Si).

5/ Separate samples shall be pulled for each bias.

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* TABLE III. Group E inspection (all quality levels) for qualification or re-qualification only.

Inspection	MIL-STD-750		Qualification and large lot quality conformance inspection
	Method	Conditions	
<u>Subgroup 1</u>			45 devices c = 0
Temperature cycling	1051	Test condition G, 500 cycles	
Hermetic seal Fine leak Gross leak	1071	As applicable	
Electrical measurements		Table I, subgroup 2 herein.	
<u>Subgroup 2</u> ^{1/}			45 devices c = 0
Steady-state gate bias	1042	Condition B, 1,000 hours.	
Electrical measurements		Table I, subgroup 2 herein.	
Steady-state reverse bias	1042	Condition A, 1,000 hours.	
Electrical measurements		Table I, subgroup 2 herein.	
<u>Subgroup 4</u>			Sample size N/A
Thermal impedance curves		See MIL-PRF-19500.	
<u>Subgroup 5</u>			15 devices c = 0
Not applicable			
<u>Subgroup 10</u>			22 devices c = 0
Commutating diode for safe operating area test procedure for measuring dv/dt during reverse recovery of power MOSFET transistors or insulated gate bipolar transistors	3476	Test conditions shall be derived by the manufacturer	
<u>Subgroup 11</u>			3 devices
SEE ^{2/} ^{3/}	1080	See figure 7.	

^{1/} A separate sample for each test shall be pulled.

^{2/} Group E qualification of SEE testing may be performed prior to lot formation. Qualification may be extended to other specification sheets utilizing the same structurally identical die design.

^{3/} Device qualification to a higher level linear energy transfer (LET) is sufficient to qualify all lower level LET's.

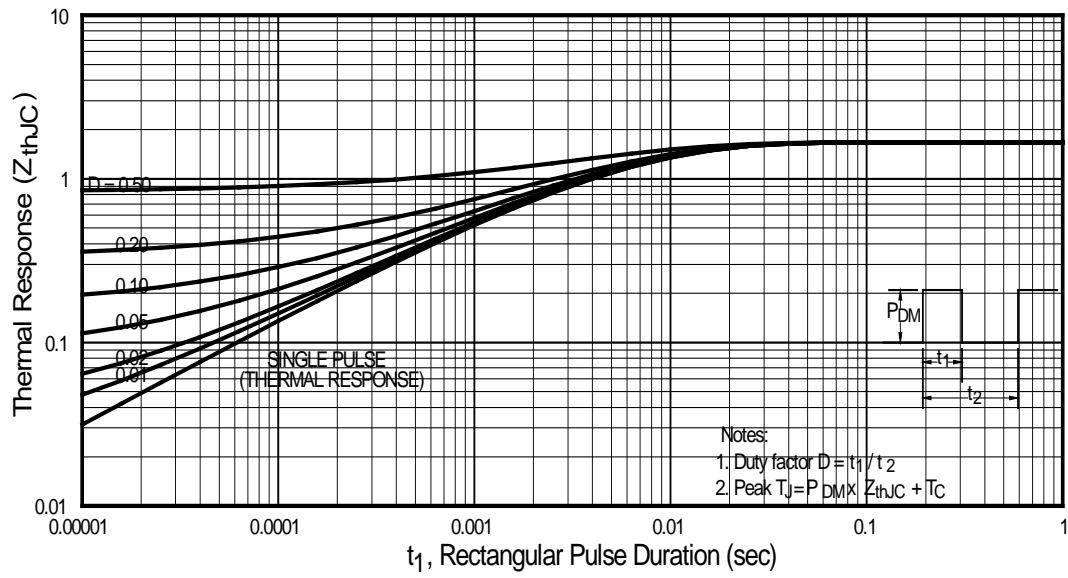


FIGURE 2. Thermal response curve.

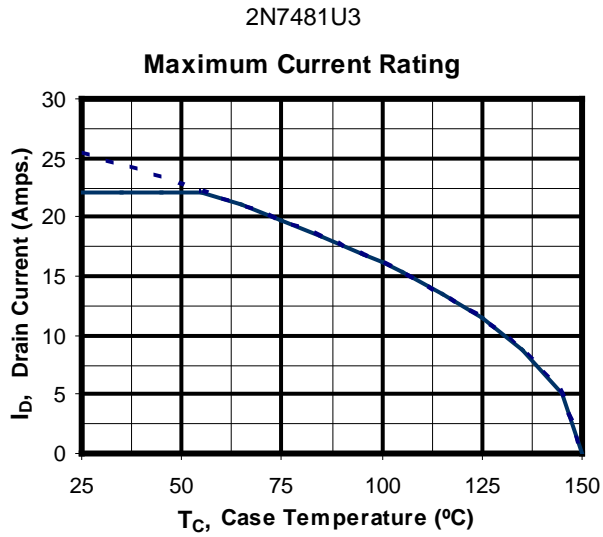
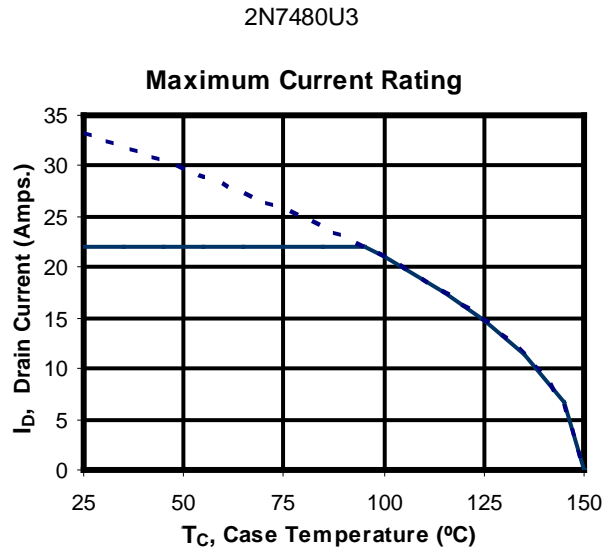
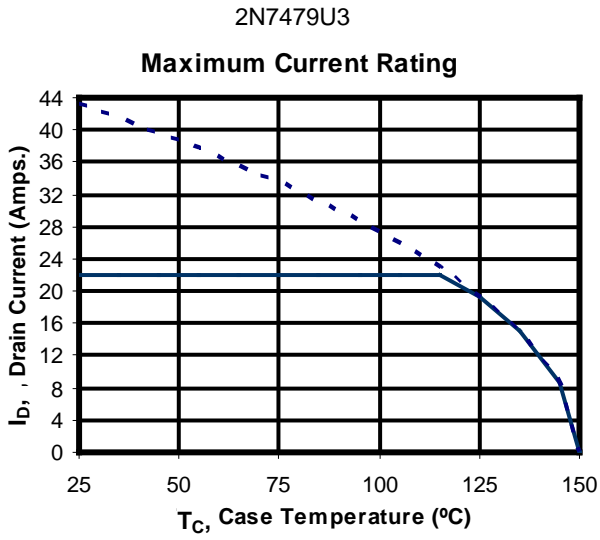


FIGURE 3. Maximum drain current versus case temperature graphs.

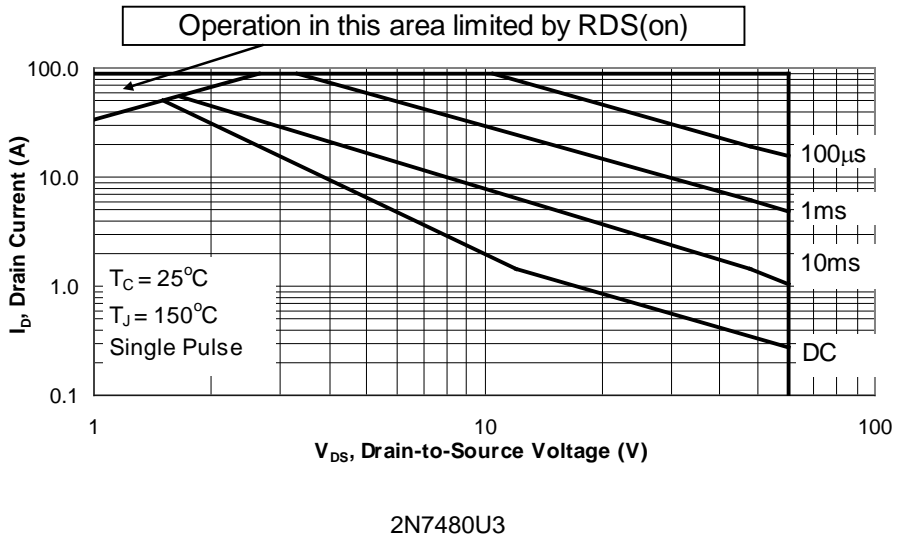
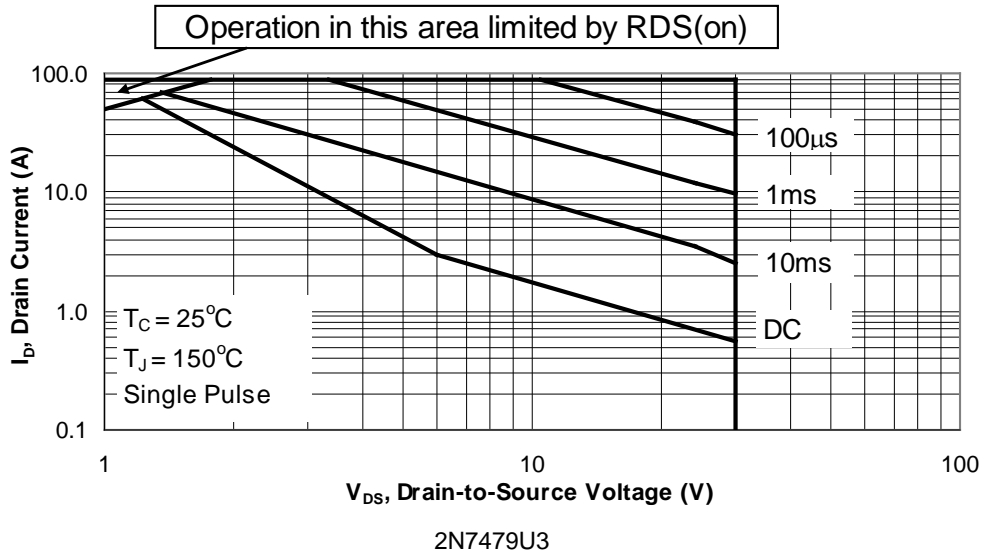


FIGURE 5. Safe operating area graph.

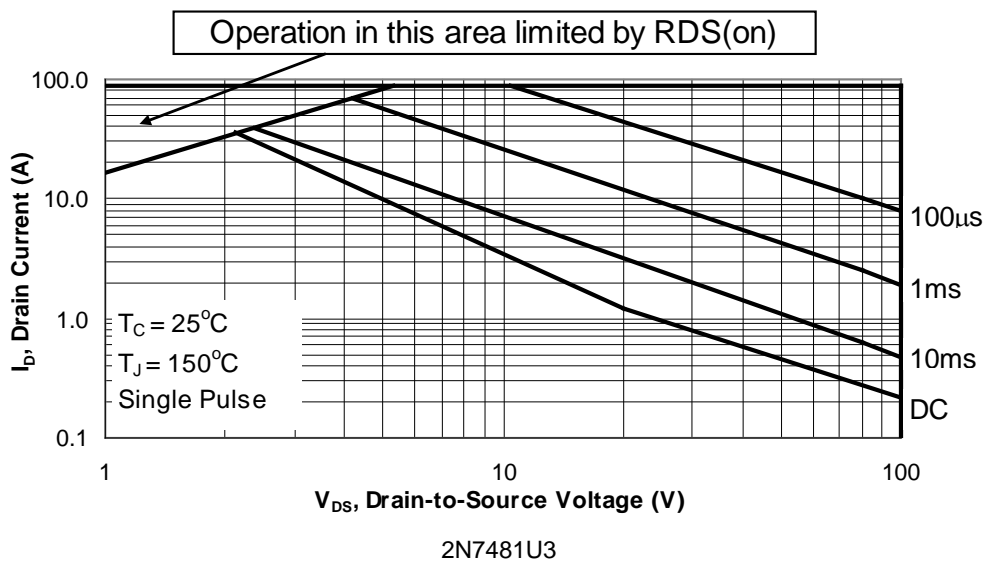


FIGURE 6. Safe operating area graph.

5. PACKAGING

5.1 Packaging. For acquisition purposes, the packaging requirements shall be as specified in the contract or order (see 6.2). When packaging of materiel is to be performed by DoD or in-house contractor personnel, these personnel need to contact the responsible packaging activity to ascertain packaging requirements. Packaging requirements are maintained by the Inventory Control Point's packaging activities within the Military Service or Defense Agency, or within the Military Service's system commands. Packaging data retrieval is available from the managing Military Department's or Defense Agency's automated packaging files, CD-ROM products, or by contacting the responsible packaging activity.

6. NOTES

(This section contains information of a general or explanatory nature that may be helpful, but is not mandatory. The notes specified in MIL-PRF-19500 are applicable to this specification.)

6.1 Intended use. Semiconductors conforming to this specification are intended for original equipment design applications and logistic support of existing equipment.

6.2 Acquisition requirements. Acquisition documents should specify the following:

- a. Title, number, and date of this specification.
- b. Packaging requirements (see 5.1).
- c. Lead finish (see 3.4.1).
- d. The complete Part or Identifying Number (PIN), see title and section 1.
- e. For acquisition of RHA designated devices, table II, subgroup 1 testing of group D herein is optional. If subgroup 1 is desired, it should be specified in the contract or order.
- f. If SEE testing data is desired, it should be specified in the contract or order.
- g. If specific SEE characterization conditions are desired (see section 6.5 and table IV), manufacturer's cage code should be specified in the contract or order.

6.3 Qualification. With respect to products requiring qualification, awards will be made only for products which are, at the time of award of contract, qualified for inclusion in Qualified Manufacturers List (QML 19500) whether or not such products have actually been so listed by that date. The attention of the contractors is called to these requirements, and manufacturers are urged to arrange to have the products that they propose to offer to the Federal Government tested for qualification in order that they may be eligible to be awarded contracts or orders for the products covered by this specification. Information pertaining to qualification of products may be obtained from DLA Land and Maritime, ATTN: VQE, P.O. Box 3990, Columbus, OH 43218-3990 or e-mail vqe.chief@dla.mil. An online listing of products qualified to this specification may be found in the Qualified Products Database (QPD) at <https://assist.dla.mil>.

6.4 Cross-reference list. The following table shows the generic P/N and its associated military P/N (without JAN and RHA prefix).

Generic P/N	Military P/N
IRHNJ57Z30	2N7479U3
IRHNJ57034	2N7480U3
IRHNJ57130	2N7481U3

6.5 Application data.

6.5.1 Manufacturer specific irradiation data. Each manufacturer qualified to this slash sheet has characterized its devices to the requirements of MIL-STD-750 method 1080 and as specified herein. Since each manufacturer's characterization conditions can be different and can vary by the version of method 1080 qualified to, the MIL-STD-750 method 1080 revision version date and conditions used by each manufacturer for characterization have been listed here (see table IV) for information only. SEE conditions and figures listed in section 6 are current as of the date of this specification sheet, please contact the manufacturer for the most recent conditions.

TABLE IV. Manufacturers characterization conditions.

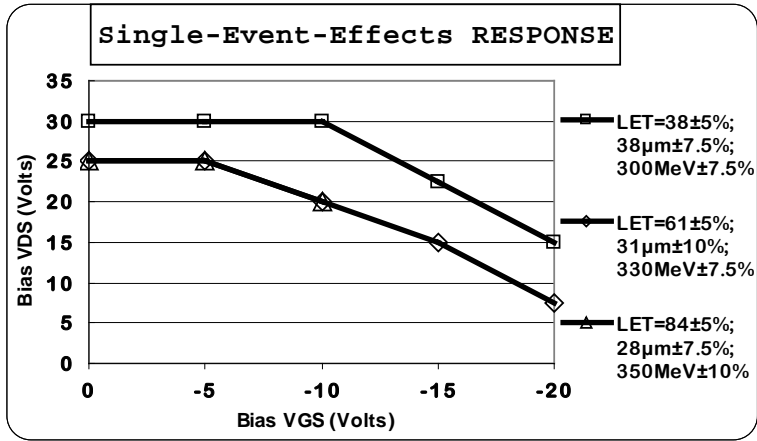
Manufactures cage	Inspection	MIL-STD-750		Sample plan
		Method	Conditions	
69210 (Applicable to devices with a date code of September 2009 and older)	SEE 1/	1080	See MIL-STD-750E method 1080.0 dated 20 November 2006. See figure 7.	3 devices
	Electrical measurements		I_{GSSF1} , I_{GSSR1} , and I_{DSS1} in accordance with table I, subgroup 2	
	SEE irradiation:		Fluence = $3E5 \pm 20$ percent ions/cm ² Flux = $2E3$ to $2E4$ ions/cm ² /sec, temperature = $25^\circ \pm 5$ °C Surface LET = $38 \text{ MeV-cm}^2/\text{mg} \pm 5\%$, range = $38 \mu\text{m} \pm 7.5\%$, energy = $300 \text{ MeV} \pm 7.5\%$	
	2N7479U3		In-situ bias conditions: $V_{DS} = 30 \text{ V}$ and $V_{GS} = -10 \text{ V}$ $V_{DS} = 22.5 \text{ V}$ and $V_{GS} = -15 \text{ V}$ $V_{DS} = 15 \text{ V}$ and $V_{GS} = -20 \text{ V}$ (nominal 3.86 MeV/nucleon at Brookhaven National Lab Accelerator)	
	2N7480U3		In-situ bias conditions: $V_{DS} = 60 \text{ V}$ and $V_{GS} = -15 \text{ V}$ $V_{DS} = 30 \text{ V}$ and $V_{GS} = -20 \text{ V}$ (nominal 3.86 MeV/nucleon at Brookhaven National Lab Accelerator)	
	2N7481U3		In-situ bias conditions: $V_{DS} = 100 \text{ V}$ and $V_{GS} = -20 \text{ V}$ (nominal 3.86 MeV/nucleon at Brookhaven National Lab Accelerator) Surface LET = $61 \text{ MeV-cm}^2/\text{mg} \pm 5\%$, range = $31 \mu\text{m} \pm 10\%$, energy = $330 \text{ MeV} \pm 7.5\%$	
	2N7479U3		In-situ bias conditions: $V_{DS} = 25 \text{ V}$ and $V_{GS} = -5 \text{ V}$ $V_{DS} = 20 \text{ V}$ and $V_{GS} = -10 \text{ V}$ $V_{DS} = 15 \text{ V}$ and $V_{GS} = -15 \text{ V}$ $V_{DS} = 7.5 \text{ V}$ and $V_{GS} = -20 \text{ V}$ (nominal 2.92 MeV/nucleon at Brookhaven National Lab Accelerator)	
2N7480U3	In-situ bias conditions: $V_{DS} = 46 \text{ V}$ and $V_{GS} = -5 \text{ V}$ $V_{DS} = 30 \text{ V}$ and $V_{GS} = -10 \text{ V}$ $V_{DS} = 25 \text{ V}$ and $V_{GS} = -15 \text{ V}$ $V_{DS} = 15 \text{ V}$ and $V_{GS} = -20 \text{ V}$ (nominal 2.92 MeV/nucleon at Brookhaven National Lab Accelerator)			

See footnotes at end of table.

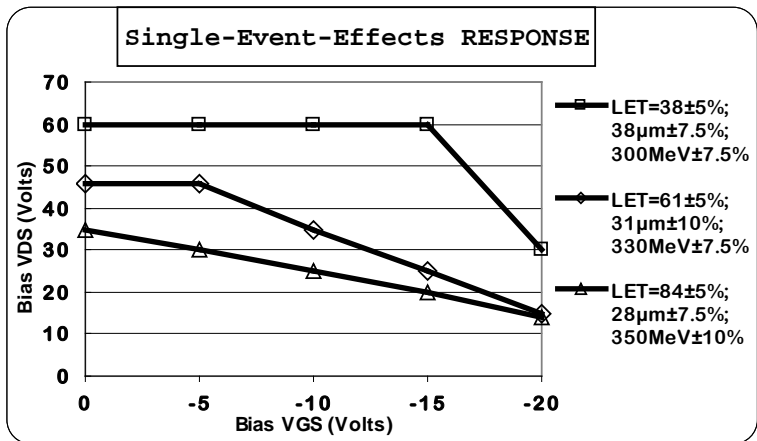
TABLE IV. Manufacturers characterization conditions - Continued.

Manufactures cage	Inspection	MIL-STD-750		Sample plan
		Method	Conditions	
	2N7481U3		In-situ bias conditions: $V_{DS} = 100\text{ V}$ and $V_{GS} = -10\text{ V}$ $V_{DS} = 35\text{ V}$ and $V_{GS} = -15\text{ V}$ $V_{DS} = 25\text{ V}$ and $V_{GS} = -20\text{ V}$ (nominal 2.92 MeV/nucleon at Brookhaven National Lab Accelerator) Surface LET = 84 MeV-cm ² /mg $\pm 5\%$, range = 28 μm $\pm 7.5\%$, energy = 350 MeV $\pm 7.5\%$	
	2N7479U3		In-situ bias conditions: $V_{DS} = 25\text{ V}$ and $V_{GS} = -5\text{ V}$ $V_{DS} = 20\text{ V}$ and $V_{GS} = -10\text{ V}$ (nominal 1.98 MeV/nucleon at Brookhaven National Lab Accelerator)	
	2N7480U3		In-situ bias conditions: $V_{DS} = 35\text{ V}$ and $V_{GS} = -5\text{ V}$ $V_{DS} = 25\text{ V}$ and $V_{GS} = -10\text{ V}$ $V_{DS} = 15\text{ V}$ and $V_{GS} = -15\text{ V}$ $V_{DS} = 10\text{ V}$ and $V_{GS} = -20\text{ V}$ (nominal 1.98 MeV/nucleon at Brookhaven National Lab Accelerator)	
	2N7481U3		In-situ bias conditions: $V_{DS} = 100\text{ V}$ and $V_{GS} = -5\text{ V}$ $V_{DS} = 80\text{ V}$ and $V_{GS} = -10\text{ V}$ $V_{DS} = 25\text{ V}$ and $V_{GS} = -15\text{ V}$ (nominal 1.98 MeV/nucleon at Brookhaven National Lab Accelerator)	
	Electrical measurements		I_{GSSF1} , I_{GSSR1} , and I_{DSS1} in accordance with table I , subgroup 2	
<div style="border: 1px solid black; padding: 5px; width: fit-content; margin: 0 auto;"> Upon qualification, all manufacturers should provide the verification test conditions to be added to this table. </div>				

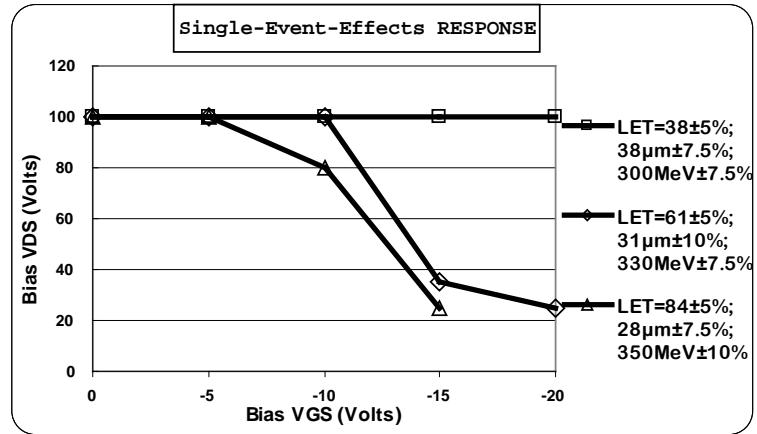
1/ I_{GSSF1} , I_{GSSR1} , and I_{DSS1} was examined before and following SEE irradiation to determine acceptability for each bias condition. Other test conditions in accordance with [table I](#), subgroup 2, may be performed at the manufacturer's option.



2N7479U3



2N7480U3



2N7481U3

FIGURE 7. SEE safe operating area graph.

- * 6.6 Changes from previous issue. The margins of this specification are marked with asterisks to indicate where changes from the previous issue were made. This was done as a convenience only and the Government assumes no liability whatsoever for any inaccuracies in these notations. Bidders and contractors are cautioned to evaluate the requirements of this document based on the entire content irrespective of the marginal notations and relationship to the previous issue.

Custodians:
Army - CR
Navy - EC
Air Force - 85
NASA - NA
DLA - CC

Preparing activity:
DLA - CC

(Project 5961-2014-122)

Review activities:
Army - AV, MI
Air Force - 99

NOTE: The activities listed above were interested in this document as of the date of this document. Since organizations and responsibilities can change, you should verify the currency of the information above using the ASSIST Online database at <https://assist.dla.mil>.